

Appl. No. : 10/657,416  
Filed : September 8, 2003

### AMENDMENTS TO THE CLAIMS

Please amend the Claim Form and Claim as follows. Insertions are shown underlined while deletions are ~~struck through~~.

1 (currently amended): A method for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate in a reactor by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;

continuously forming a second insulation film on the first insulation film in the same reactor at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and

subjecting the second insulation film to polishing for forming a subsequent layer thereon.

2 (currently amended): ~~The~~A ~~method as claimed in Claim 1~~for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;

continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and

subjecting the second insulation film to polishing for forming a subsequent layer thereon,

wherein the first insulation film has a hardness of less than 6 GPa, and the second insulation film has a hardness of no less than 6 GPa.

3 (currently amended): ~~The~~A ~~method as claimed in Claim 1~~for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;

continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and  
subjecting the second insulation film to polishing for forming a subsequent layer thereon,  
wherein the first source gas further comprises an oxidizing gas having a flow rate which is less than 1.0 times that of the silicon-containing hydrocarbon gas.

4 (currently amended): ~~The~~A ~~method as claimed in Claim 1~~for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;  
continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and  
subjecting the second insulation film to polishing for forming a subsequent layer thereon,  
wherein the oxidizing gas in the second source gas has a flow rate which is more than 1.0 times that of the silicon-containing hydrocarbon gas.

5 (original): The method as claimed in Claim 4, wherein the second insulation film is formed under conditions where RF power is reduced and the flow rate of the silicon-containing hydrocarbon is reduced, as compared with those for the first insulation film.

6 (currently amended): ~~The~~A ~~method as claimed in Claim 1~~for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;  
continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and  
subjecting the second insulation film to polishing for forming a subsequent layer thereon,

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wherein the silicon-containing hydrocarbon in the second source gas has the formula  $\text{Si}_\alpha\text{O}_{\alpha-1}\text{R}_{2\alpha-\beta+2}(\text{OC}_n\text{H}_{2n+1})_\beta$  where  $\alpha$  is an integer of 1-3,  $\beta$  is an integer of 0-2,  $n$  is an integer of 1-3, and  $\text{R}$  is  $\text{C}_{1-6}$  hydrocarbon attached to  $\text{Si}$ .

7 (original): The method as claimed in Claim 6, wherein the silicon-containing hydrocarbon is dimethy-dimethoxysilane.

8 (currently amended): The method as claimed in Claim 43, wherein the oxidizing gas is at least one selected from the group consisting of oxygen, dinitrogenoxide, ozone, hydrogen peroxide, carbon dioxide, and polyalcohol.

9 (currently amended): The method as claimed in Claim 43, wherein the silicon-containing hydrocarbon gas in the first source gas and the silicon-containing hydrocarbon gas in the second source gas are the same gas.

10 (currently amended): The method as claimed in Claim 1 for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;

continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and  
subjecting the second insulation film to polishing for forming a subsequent layer thereon,  
wherein the first source gas comprises no oxidizing gas.

11 (currently amended): The method as claimed in Claim 1 for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;

continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and  
subjecting the second insulation film to polishing for forming a subsequent layer thereon,

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wherein the second insulation film is composed of multiple layers having different oxygen contents.

12 (currently amended): ~~The~~A ~~method as claimed in Claim 1~~for forming an interlayer insulation film for multilayer interconnect of a semiconductor integrated circuit, comprising the steps of:

forming a first insulation film on a substrate by plasma CVD using a first source gas comprising a silicon-containing hydrocarbon gas;

continuously forming a second insulation film on the first insulation film at a thickness less than the first insulation film *in situ* by plasma CVD using a second source gas comprising a silicon-containing hydrocarbon gas and an oxidizing gas; and  
subjecting the second insulation film to polishing for forming a subsequent layer thereon,  
said method further comprising forming via holes and/or trenches in the first and second insulation films, and filling the holes and/or trenches with copper for interconnect, wherein the polishing conducted thereafter is chemical mechanical polishing (CMP).

13-21 (canceled)